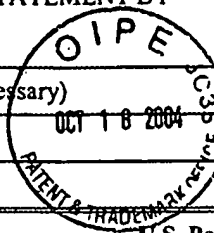


U.S. Department of Commerce, Patent and Trademark	Atty. Docket No.	Application No.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	TNCR.178US1	10/613,634
	Applicant(s)	Conf. No.
(Use several sheets if necessary)	Wayne Chen et al.	4612
	Filing Date	Group
	July 3, 2003	2877



## U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
MS	1	5,699,447	Dec., 1997	Alumot et al.			
MS	2	5,864,394	Jan., 1999	Jordan, III et al.			
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## U.S. Published Patent Application Documents

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## Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

MS	6	"Acoustic Scanners and Modulators," M. Gottlieb, Optical Scanning, ed. by Gerald F. Marshall, Dekker 1991, pp. 615-685.						
MS	7	"CMP Applications for Sub-0.25.mu.m Process Technologies," D. Pramanik et al., presented at Electrochemical Society Proceedings: Chemical Mechanical Planarization in IC Device Manufacturing (2.sup.nd International Symposium), vol. 98-7, 1998.						
MS	8	Integrated CMP Defect Monitoring Strategy," W. Chen et al., presented at The Electrochemical Society Proceedings: Chemical Mechanical Polishing in IC Device Manufacturing III, Editors: V.A. Arimoto et la., PV99-37, Honolulu, Oct. 1999.						

Examiner Michael Stefan Date Considered 2-22-05

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.